L Number	Hits	Search Text	DB	Time stamp
1	467577	integrated near circuit	USPAT; US-PGPUB; EPO; JPO;	2004/06/18 07:13
2	355	(porous same (silica silicate silicalite)) and (((binder) same (radiation photosensitive ultraviolet)) )	DERWENT USPAT; US-PGPUB; EPO; JPO;	2004/06/18 07:45
3	4	(integrated near circuit) and ((porous same (silica silicate silicalite)) and (((binder) same (radiation photosensitive ultraviolet)) ))	DERWENT USPAT; US-PGPUB; EPO; JPO;	2004/06/18 07:14
4	76	(porous near (silica silicate silicalite (silicon near dioxide) sio?sub.2)) and (((binder) same (radiation photosensitive ultraviolet)))	DERWENT USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 07:46
5	2	(integrated near circuit) and ((porous near (silica silicate silicalite (silicon near dioxide) sio?sub.2)) and (((binder) same (radiation photosensitive ultraviolet)) ))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 07:46
6	0	((integrated near circuit) and ((porous near (silica silicate silicalite (silicon near dioxide) sio?sub.2)) and (((binder) same (radiation photosensitive ultraviolet)) ))) not ((integrated near circuit) and ((porous same (silica silicate silicalite)) and (((binder) same (radiation photosensitive ultraviolet)) )))	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 07:51
7	34917	((tolinder) same (radiation photoseristive diffaviolety) ))) (integrated near circuit) and (metal near layer)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 07:51
8	17576	((integrated near circuit) and (metal near layer)) and wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:00
9	8079	(((integrated near circuit) and (metal near layer)) and wafer) and (dielectric near layer)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:00
10	1045	((((integrated near circuit) and (metal near layer)) and wafer) and (dielectric near layer)) and silica	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:00
11	6563	((integrated near circuit) and (metal near layer)) and (silicon near wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:00
12	3025	(((integrated near circuit) and (metal near layer)) and (silicon near wafer)) and (dielectric near layer)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:00
13	7	((((integrated near circuit) and (metal near layer)) and (silicon near wafer)) and (dielectric near layer)) and 252/570;524/588;522/99,148;528/32.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/06/18 08:01